



## The Objective

- Learn the fundamentals of plasma etching, plasma reactors, and etching mechanisms
- Review state-of-the-art etching technologies for deep silicon etching, compound semiconductors, dielectrics, and metals
- Understand the fundamentals of endpoint detection
- Q&A regarding specific plasma etching projects

## Content

- Vacuum Basics
- Plasma Basics
- Plasma Reactors
- Plasma Etching Mechanisms
- Compound Semiconductor Etching
- Deep Silicon Etching
- Dielectric Etching
- Metal Etching
- Endpoint Basics
- Sample Thermal Management

**Faculty, students, local companies, local universities are welcomed to attend**

Networking activities include:  
Continental breakfast and lunch will be provided

## Presented by:

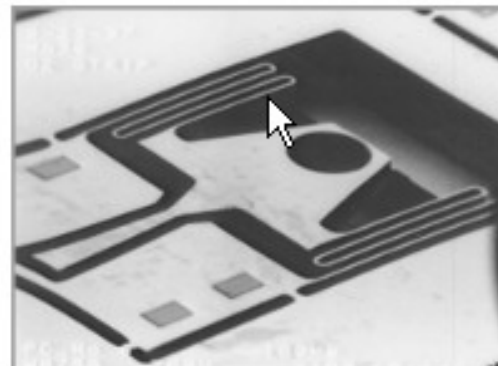
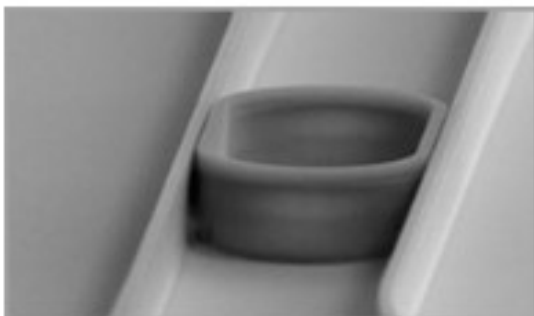
- David Lishan Ph.D. Electrical Engineering
- Chris Johnson B.S. Materials Science and Engineering

**Date:** 01/20/2012

**Time:** 7:30 AM-6:00 PM

**Location:** CUTR 102

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MEMS microactuator